

Fig. 1(a)

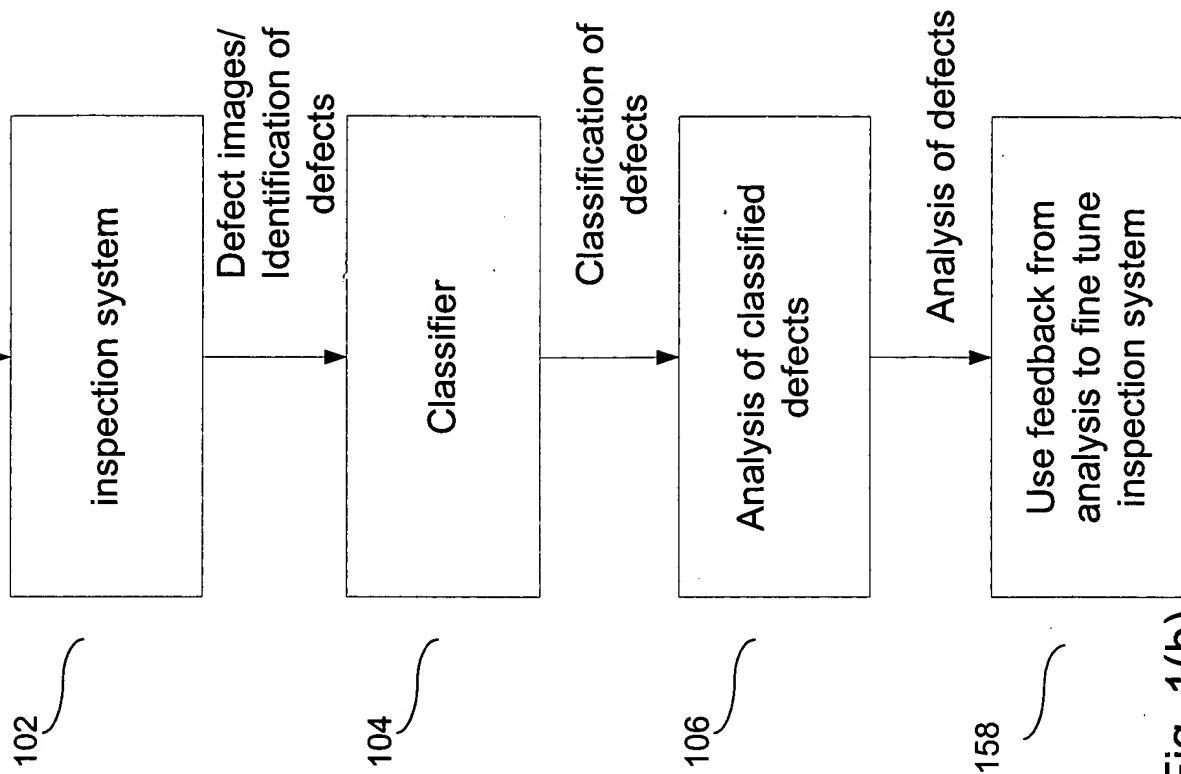


Fig. 1(b)

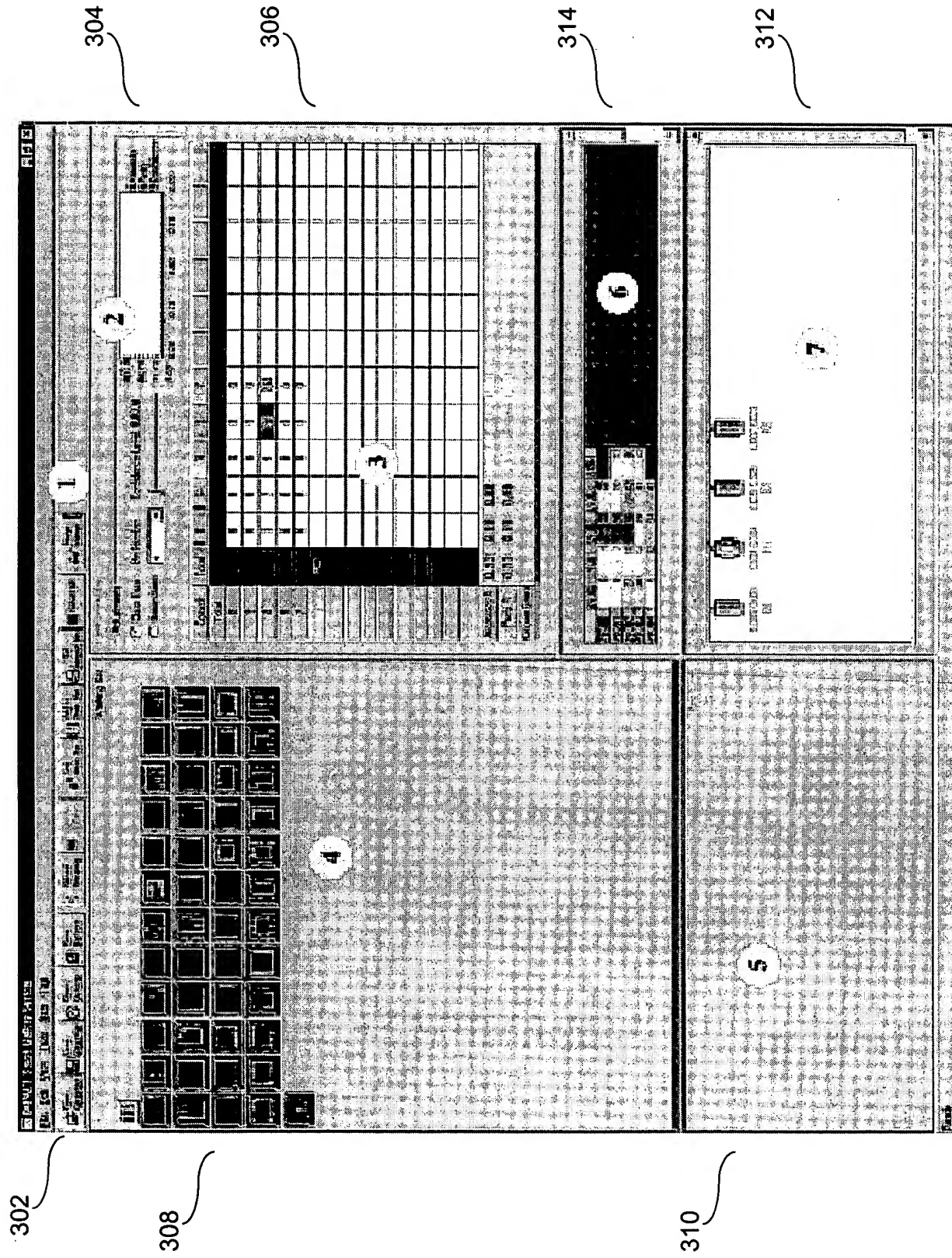


Fig. 3
Smart Gallery window

502

Sort Properties

X

Working Set

Training Set

Primary Key

☒ Lot - Wafer

☐ Manual Bin

☐ Suggested Bin

☐ Size

Secondary Key

☐ Lot - Wafer

☐ Manual Bin

☐ Suggested Bin

☐ Size

OK

Reset

Cancel

Fig. 5(a)

Sort Properties

Working Set

Training Set

Primary Key

Secondary Key

Lot - Wafer

Manual Bin

Suggested Bin

Size

Lot - Wafer

Manual Bin

Suggested Bin

Size

OK

Reset

Cancel

Fig. 5(b)

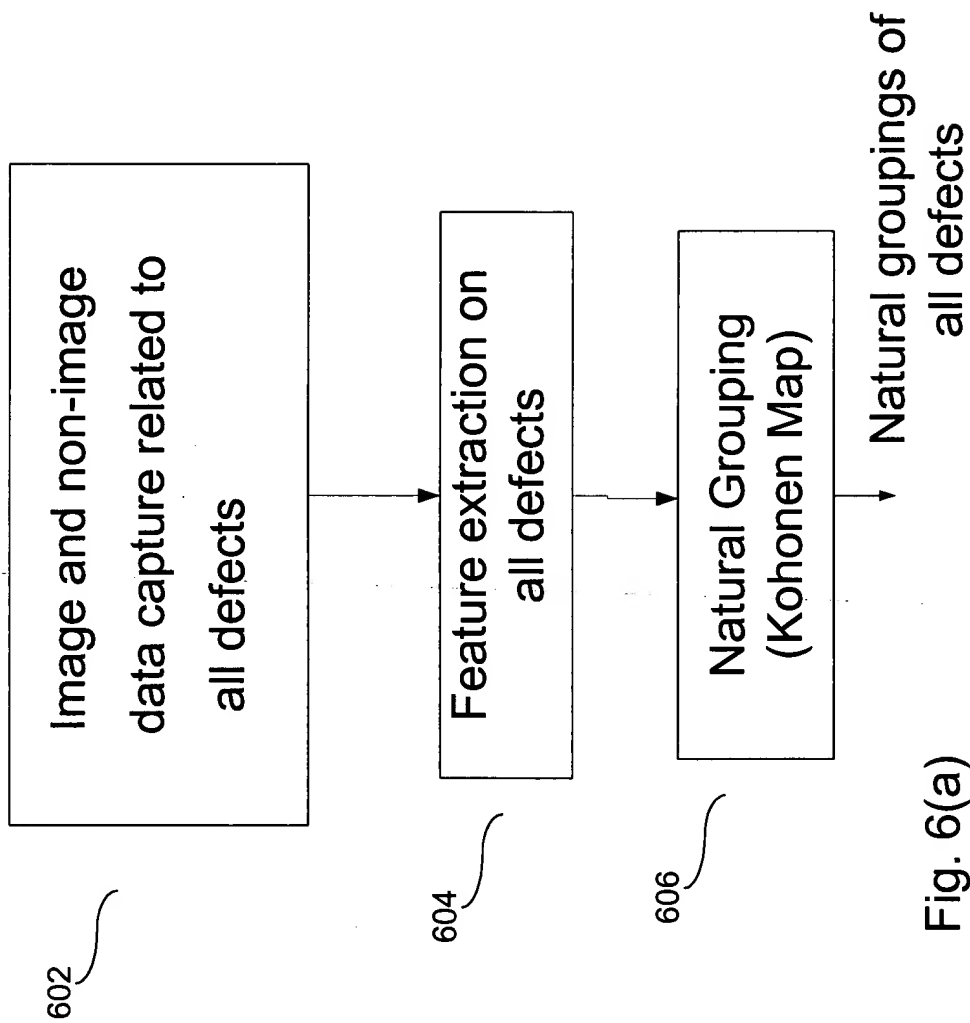


Fig. 6(a)

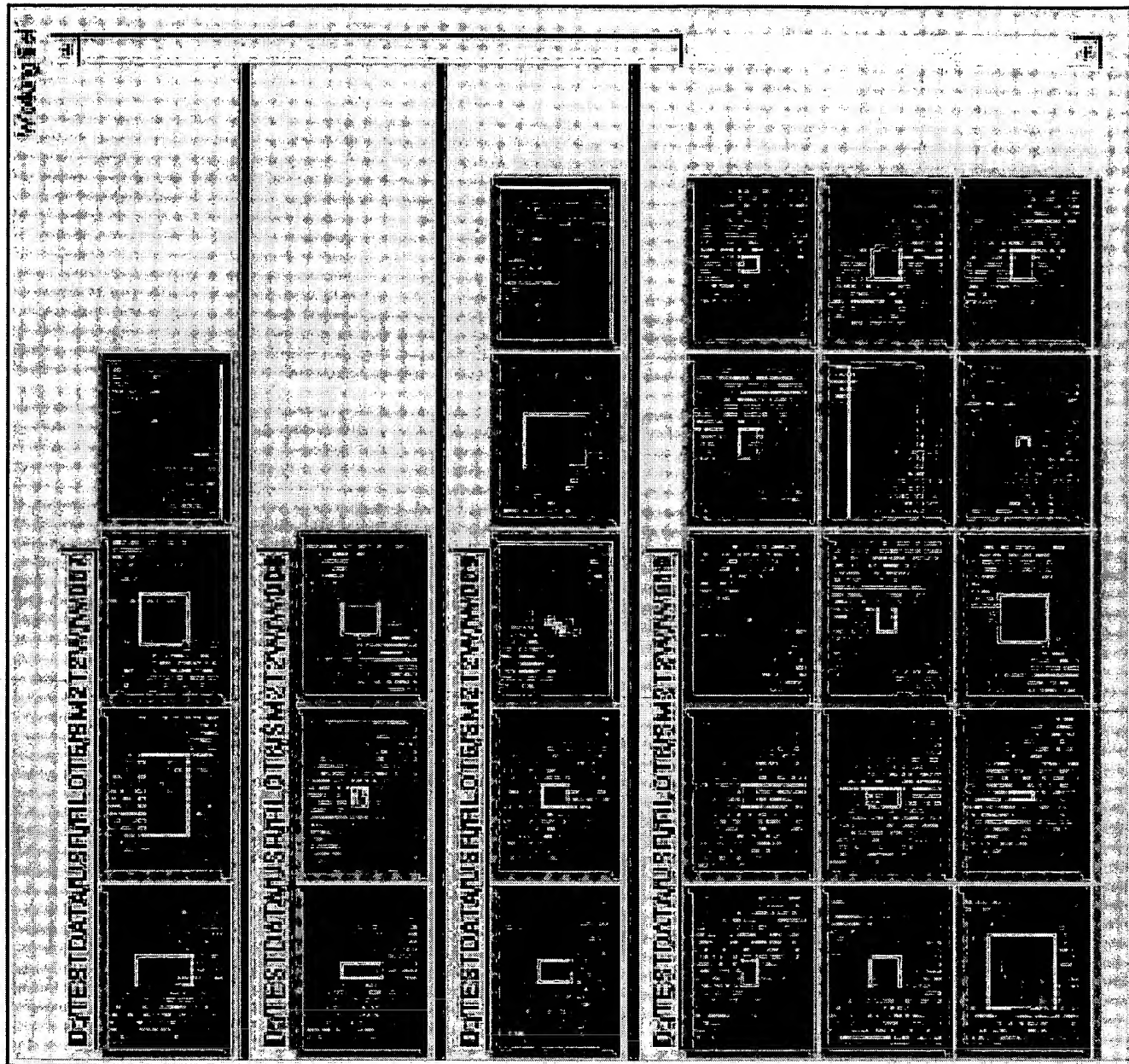


Fig. 6(b)

312

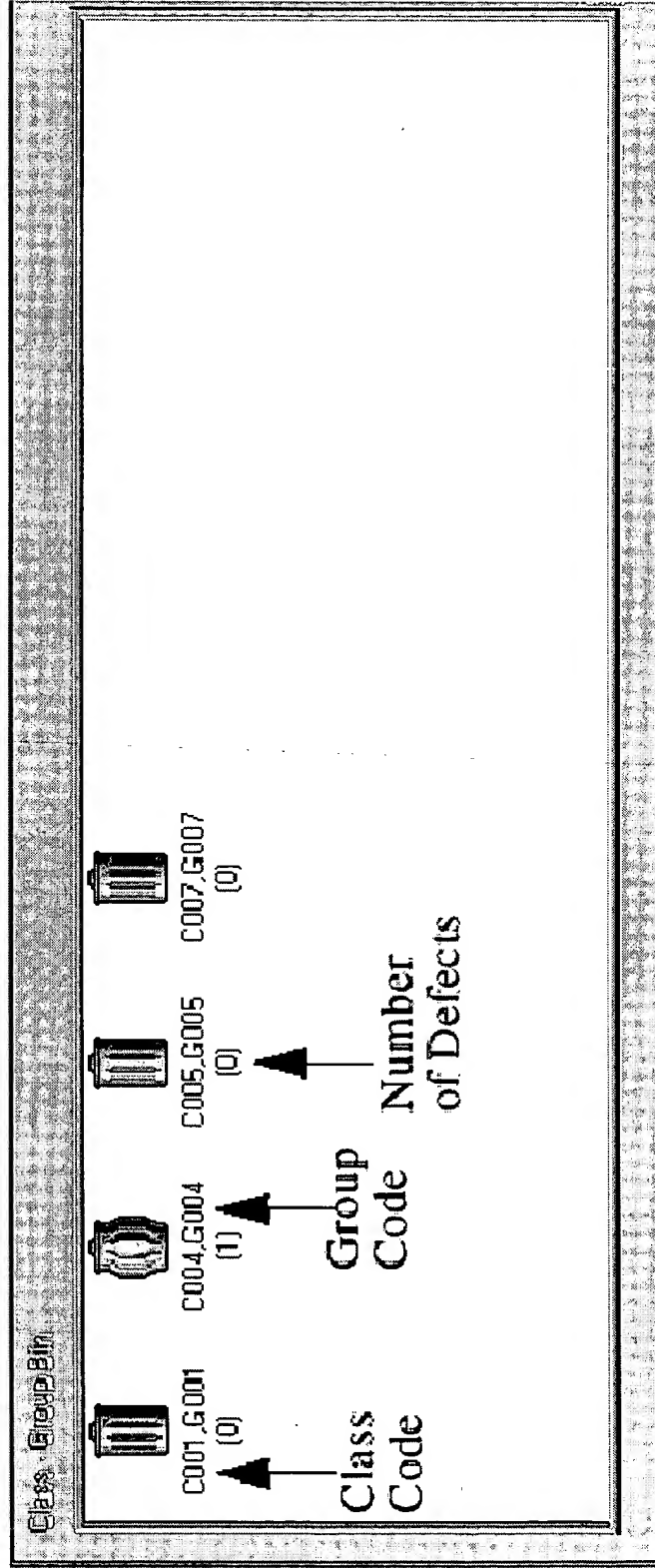
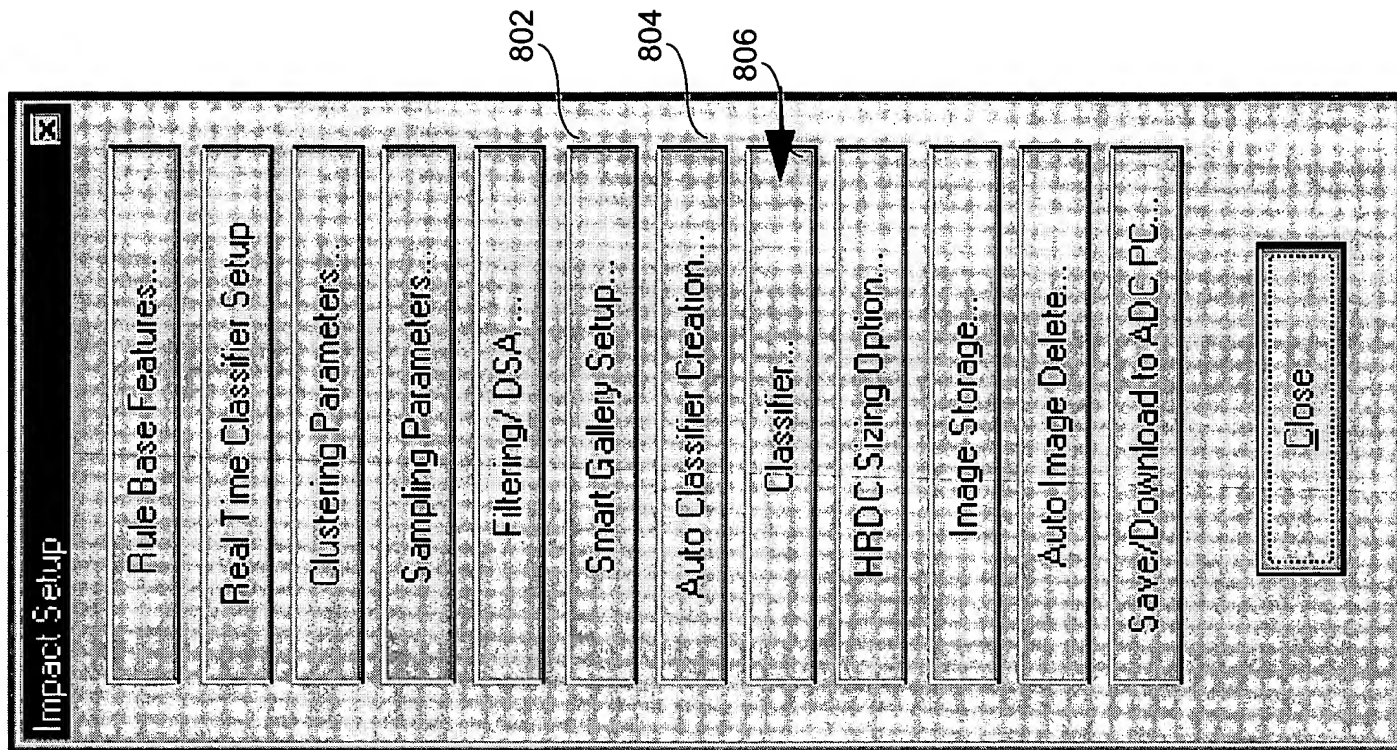


Fig. 7

Fig. 8



HRDC Classifier

X

Add Defects...

Maps opened: 0

Auto Features

Defects added: 0

☐ Select best set in

15 min

No. of features to select: 80

No. of features selected: 0

Defects to be trained: 0

Clear

Train

Filtering

Remove Group...

Defects removed: 0

Remove Defects...

Defects: 0

Filter Defects

Min defs/class: 0

Adjust Confidence

☒ Adjust confidence manually

Test (Training Set)

☐ Characterize

Test (Other)...

Close

Fig. 9

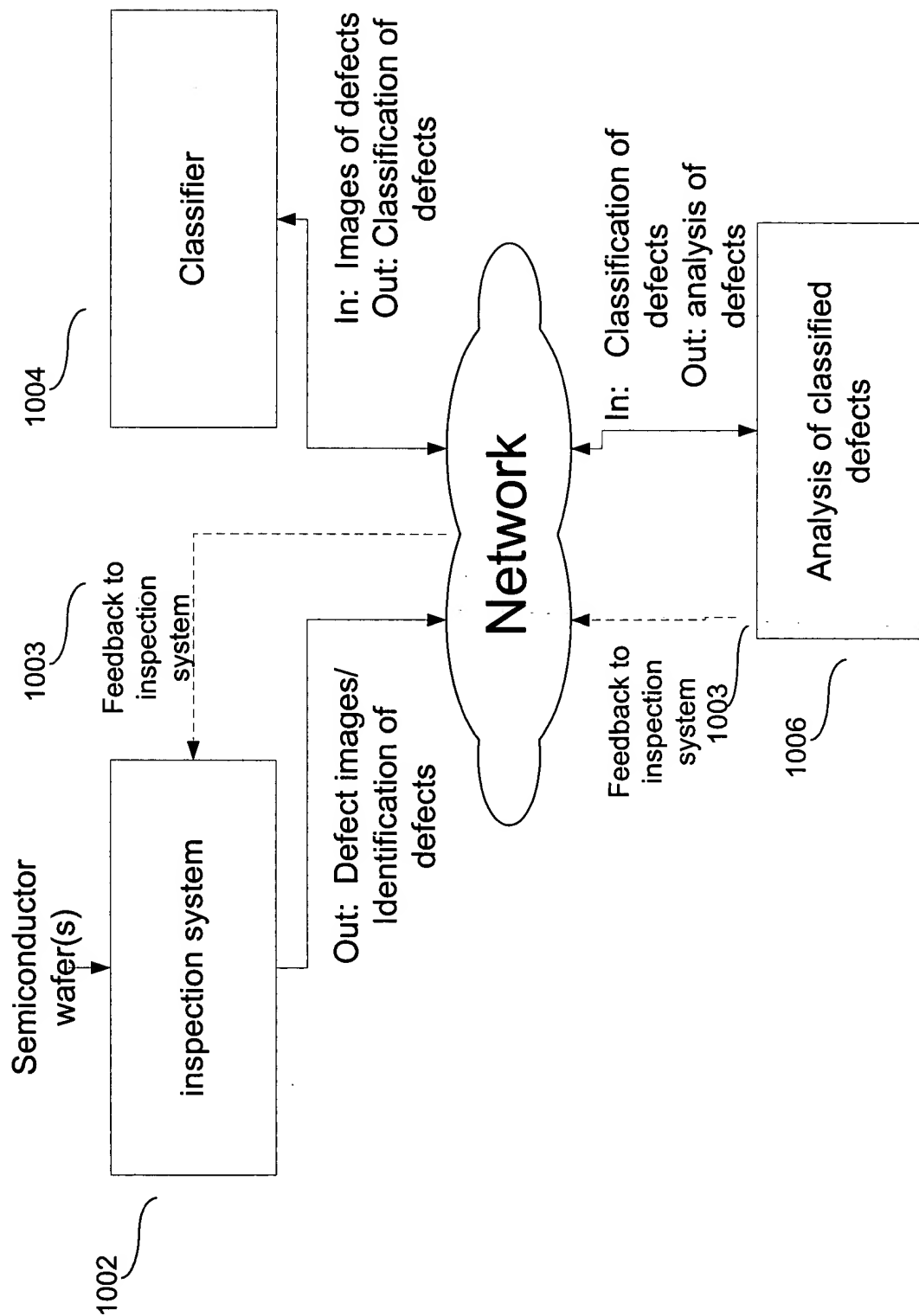


Fig. 10(a)

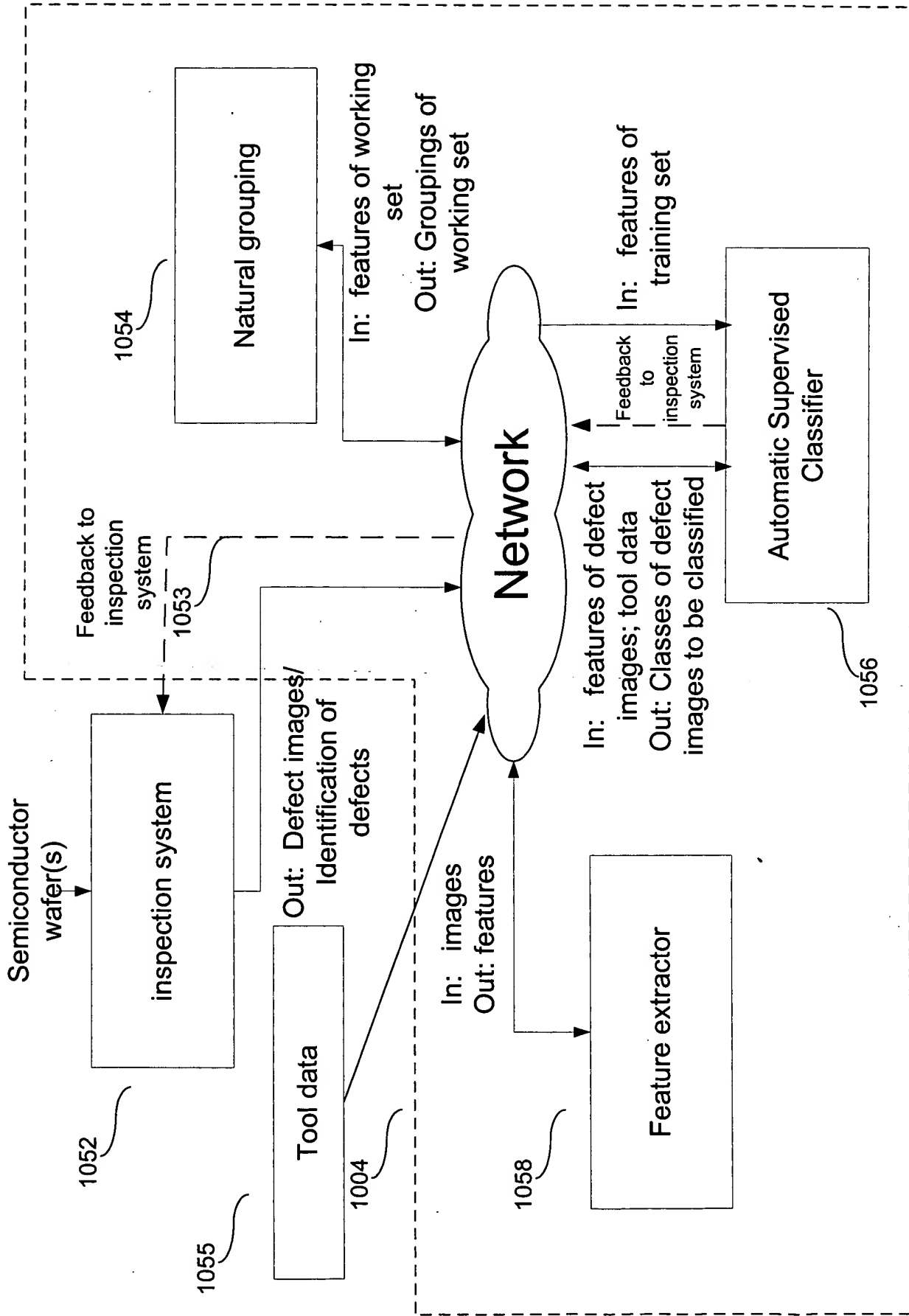


Fig. 10(b)

Semiconductor

wafer(s)

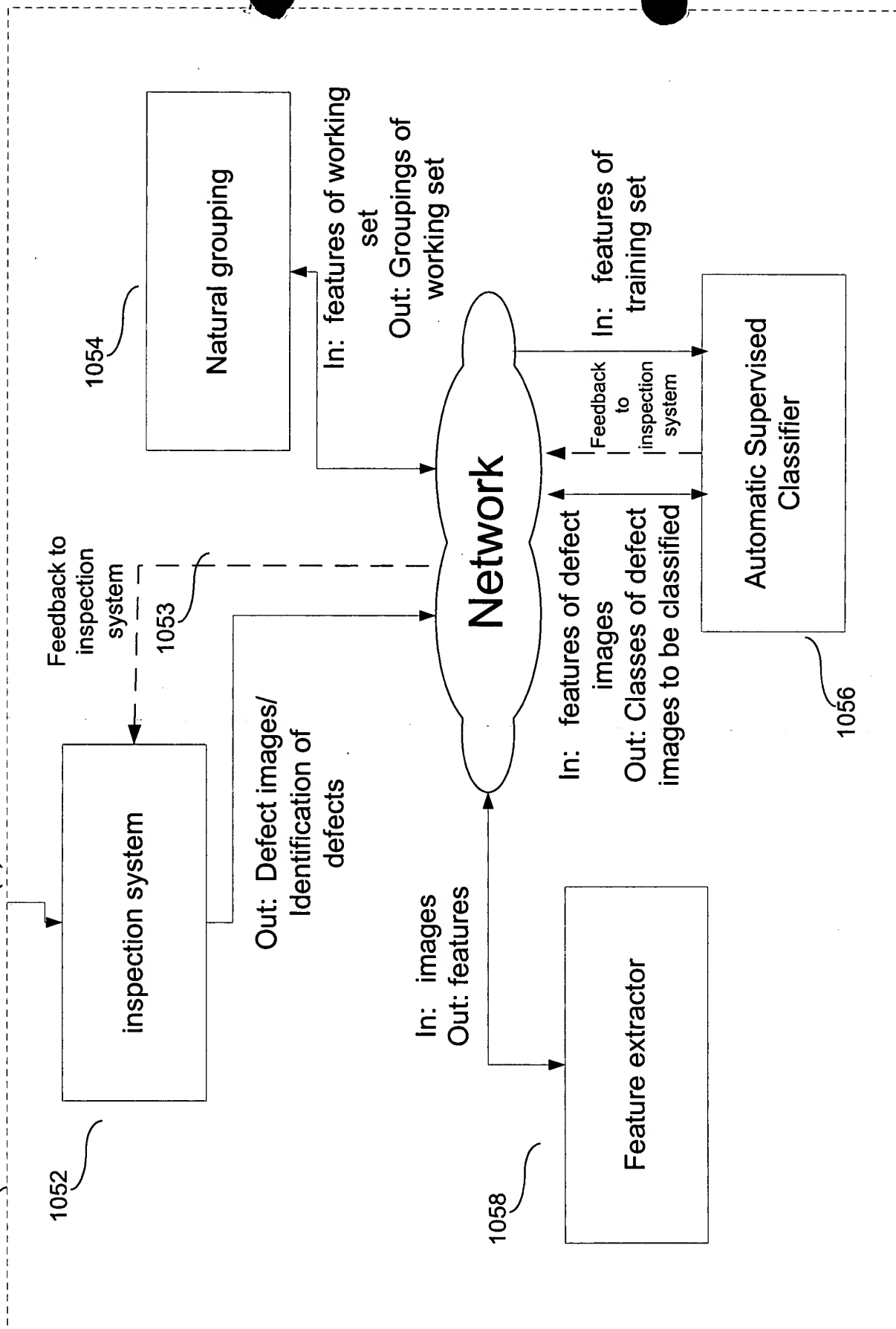


Fig. 10(c)